

Electronic Patent Application Fee Transmittal

Application Number:	10511883			
Filing Date:	19-Oct-2004			
Title of Invention:	Apparatus and method for depositing thin film on wafer using remote plasma			
First Named Inventor/Applicant Name:	Young Hoon Park			
Filer:	James J. Merrick			
Attorney Docket Number:	YPL-0108			
Filed as Large Entity				
U.S. National Stage under 35 USC 371 Filing Fees				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				
Extension-of-Time:				
Extension - 3 months with \$0 paid	1253	1	1050	1050

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Total in USD (\$)				1050